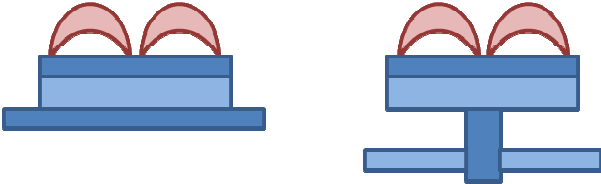
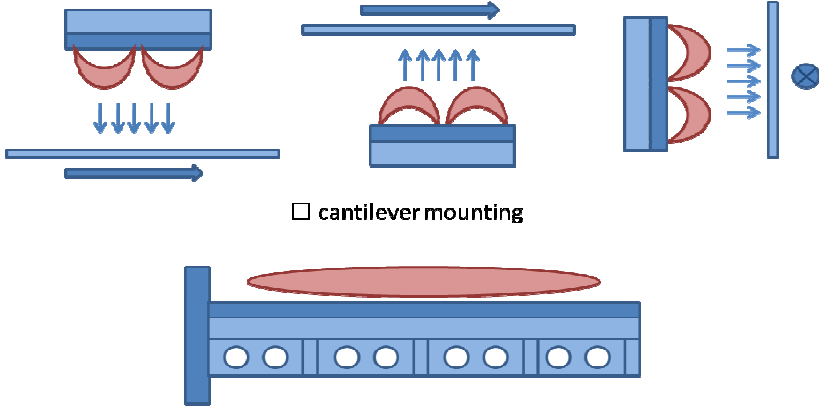


**Check List**  
**Magnetron Sputtering Sources**  
 for in-line deposition

<b>1 Contact details</b>		
	Institute/Company/Facility:	
	Process/Application	
	Contact person:	
	Phone/Fax/email	
<b>2 Film properties</b>		
2.1.	Coating/film composition	
2.2.	Substrate/Film materials	
2.3.	Requested film thickness	
2.4.	Substrate width	
2.4.	Film thickness inhomogeneity ± xx % for substrate of width yy mm	
2.5.	target-substrate distance	
2.6.	Substrate speed (m/min)	
<b>3 Magnetron properties</b>		
3.1.	Target materials	
3.2.	Clamp or bond targets?	
3.2.	Clamp target dimensions (width x length x thickness )	
3.3.	Bond target dimensions (width x length x thickness )	
3.4.	Magnetic targets	
3.6.	Operation mode/ power supply DC / DC- pulsed/ RF; Dual magnetron operation	
3.7.	Deposition rates / thickness	

**Check List**  
**Magnetron Sputtering Sources**  
for in-line deposition

<b>4</b>	<b>Mounting style</b>	
4.1.	Flange mount or internal	<input type="checkbox"/> flange mounting <input type="checkbox"/> internal mounting 
4.2.	Specify mounting interface	
4.3.	Double cathode on one plate	
4.4.	Mounting situation	<input type="checkbox"/> Sputter down <input type="checkbox"/> Sputter up <input type="checkbox"/> vertical mount  <input type="checkbox"/> cantilever mounting
<b>5</b>	<b>Electric power connection</b>	
5.1.	screw terminals	
5.2.	Other - please specify	
5.3.	Matchbox mounted on flange	
<b>6</b>	<b>Gas distribution lines</b>	
6.1.	Argon Yes/No	
6.2.	Reactive gases?	
	How many zones?	
<b>7</b>	<b>Related topics</b>	
	Brand of power supply- if known	
	Brand of matchbox - if known	
	ion- assisted deposition, e.g. unbalanced magnet array needed?	
	First setup and training wanted/needed?	

Date: \_\_\_\_\_ Signature: \_\_\_\_\_